12/30/06 Enter

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

LEE, Ho

Assignee:

SAMSUNG ELECTRONICS CO., LTD.

Title:

CHEMICAL VAPOR DEPOSITION APPARATUS

Application No.:

10/750,023

Filing Date:

December 31, 2003

Examiner:

Jeffrie Robert Lund

Group Art Unit:

1763

Docket No.:

AB-1350 US

Confirmation No.:

9344

San Jose, California December 15, 2006

Mail Stop Amendment COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, VA 22313-1450

AMENDMENT

Dear Sir:

In response to the Final Office Action having a mailing date of October 16, 2006, please amend the application as set forth below.

Claim listing begins on page 2 of this paper.

Remarks begin on page 4 of this paper.

LAW OFFICES OF MacPherson, Kwok, Chen & Heid LLP

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